WHAT IS CLAIMED IS:

| 1 | 1. A micromachined device for receiving and retaining a liquid |
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| 2 | droplet at a desired site, the device comprising: |
| 3 | a substrate having an upper surface; and |
| 4 | a three-dimensional, thin film well patterned at the upper surface of |
| 5 | the substrate wherein the well is capable of receiving and retaining a known quantity |
| 6 | of liquid at the desired site through surface tension. |
| | |
| 1 | 2. A micromachined device for receiving and retaining at least |
| 2 | one liquid droplet at a desired site, the device comprising: |
| 3 | a substrate having an upper surface; |
| 4 | a first three-dimensional, thin film well patterned at the upper surface |
| 5 | of the substrate wherein the first well is capable of receiving and retaining a first |
| 6 | known quantity of liquid at the desired site through surface tension; and |
| 7 | a second three-dimensional, thin film well patterned at the upper |
| 8 | surface of the substrate wherein the second well is patterned outside and concentric |
| 9 | to the first well wherein the second well is capable of receiving and retaining a |
| 10 | second known quantity of liquid at the desired site through surface tension. |
| | |
| 1 | A micromachined device for receiving and retaining a plurality |
| 2 | of separate liquid droplets at desired sites, the device comprising: |
| 3 | a substrate having an upper surface; and |
| 4 | an array of three-dimensional, thin film wells patterned at the upper |
| 5 | surface of the substrate wherein each of the wells is capable of receiving and |
| 6 | retaining a known quantity of liquid at one of the desired sites through surface |
| 7 | tension. |
| | |
| 1 | A micromachined device for receiving and retaining a plurality |
| 2 | of separate liquid droplets at desired sites, the device comprising: |
| 3 | a substrate having an upper surface; |
| 4 | a first array of three-dimensional, thin film wells patterned at the |
| 5 | upper surface of the substrate wherein each of the wells is capable of receiving and |

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| 6 | retaining a kno | own o | quantity of liquid at one of the desired sites through surface | |
|----|---|--------|--|--|
| 7 | tension; and | | | |
| 8 | : | a seco | and array of three-dimensional, thin film wells patterned at the | |
| 9 | upper surface of the substrate wherein each well of the second array of wells | | | |
| 10 | patterned outside and concentric to one well of the first array of wells to receive and | | | |
| 11 | retain a second | knov | n quantity of liquid at the desired site through surface tension | |
| 1 | : | 5. | The device as claimed in claim 3 wherein each of the wells is | |
| 2 | a ring. | | | |
| 1 | , | 6. | The device as claimed in claim 3 wherein the device is a | |
| 2 | microsensor an | ıd wh | erein each of the desired sites is a sensing site. | |

- The device as claimed in claim 6 wherein the microsensor is a solid-state, liquid chemical sensor.
- 1 8. The device as claimed in claim 6 wherein the microsensor is 2 a gas sensor.
- 9. The device as claimed in claim 6 wherein the microsensor is
 an optical sensor.
- 1 10. The device as claimed in claim 3 wherein the device is a 2 biomedical test plate.
- 11. The device as claimed in claim 3 wherein each of the wells is
 2 made of a photo-patternable material.
- 1 12. The device as claimed in claim 11 wherein the photo-2 patternable material is a negative photo-patternable material.
- 13. The device as claimed in claim 12 wherein the negative photo patternable material is a polymer.

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polyimide.

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| 1 | 15. The device as claimed in claim 12 wherein the negative photo- | | |
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| 2 | patternable material is an epoxy. | | |
| 1 | 16. The device as claimed in claim 15 wherein the epoxy is SU8. | | |
| 1 | 17. The device as claimed in claim 3 wherein the substrate is a | | |
| 2 | semiconductor substrate. | | |
| 1 2 | 18. The device as claimed in claim 17 wherein the semiconductor substrate includes a silicon wafer. | | |
| 1 | 19. The device as claimed in claim 18 wherein the semiconductor | | |
| 2 | substrate further includes a layer of insulating material on which the wells are | | |
| 3 | patterned. | | |
| 1 | 20. The device as claimed in claim 3 wherein the substrate is made | | |
| 2 | of a material other than a semiconductor material. | | |
| | | | |
| 1 | 21. The device as claimed in claim 3 wherein the device is a | | |
| 2 | potentiometric liquid chemical sensor and wherein each desired site is a sensing site. | | |
| 1 | 22. The device as claimed in claim 3 wherein the device is an | | |
| 2 | integrated ion sensor and wherein each desired site is a sensing site. | | |
| | | | |
| 1 | 23. The device as claimed in claim 3 wherein each of the wells | | |
| 2 | includes a side wall having an outside corner with a small radius to prevent its liquid | | |
| 3 | droplet from flowing down outside the side wall. | | |

The device as claimed in claim 13 wherein the polymer is a

| 1 | 24. A method of making a micromachined device which is capable | | |
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| 2 | of receiving and retaining at least one liquid droplet, the method comprising: | | |
| 3 | providing a substrate having a layer of radiation-sensitive material | | |
| 4 | formed thereon; and | | |
| 5 | patterning at least one three-dimensional, thin film well from the layer | | |
| 6 | of material wherein the at least one well is capable of receiving and retaining a | | |
| 7 | known quantity of liquid through surface tension. | | |
| | | | |
| 1 | 25. The method as claimed in claim 24 further comprising | | |
| 2 | patterning a three-dimensional, thin film well from the layer of material outside and | | |
| 3 | concentric to the at least one well at the same time as patterning the at least one well. | | |
| | | | |
| 1 | 26. The method as claimed in claim 24 wherein the layer of | | |
| 2 | material is photo-patternable. | | |
| | | | |
| 1 | 27. A method of using the device as claimed in claim 1, the | | |
| 2 | method comprising: | | |
| 3 | dispensing a membrane solution droplet into the well. | | |
| | | | |
| 1 | 28. The method as claimed in claim 27 wherein the membrane | | |
| 2 | solution is a polymeric membrane solution. | | |

- 1 29. The method as claimed in claim 27 wherein the membrane solution is an aqueous solution.
- 30. The method as claimed in claim 27 wherein the membrane
 solution is a solvent-based solution.
- 31. The method as claimed in claim 27 wherein the membrane is
 an optical membrane.
- 32. A method of using the device as claimed in claim 2, the
 method comprising:

6

| 3 | dispensing a first membrane solution droplet into the first well; and | | | |
|---|---|--|--|--|
| 4 | dispensing a second membrane solution droplet over the first | | | |
| 5 | membrane solution droplet and into the second well. | | | |
| | | | | |
| 1 | 33. The method as claimed in claim 32 wherein the first membrane | | | |
| 2 | solution is an internal filling solution. | | | |
| | | | | |
| 1 | 34. The method as claimed in claim 32 wherein the second | | | |
| 2 | membrane solution is an external binding layer. | | | |
| | | | | |
| 1 | 35. The method as claimed in claim 32 wherein the second | | | |
| 2 | membrane solution has enzymes, antibodies or functional groups trapped therein. | | | |
| | | | | |
| 1 | 36. A method of using the device as claimed in claim 3, the | | | |
| 2 | method comprising: | | | |
| 3 | dispensing a membrane solution droplet into each of the array of | | | |
| 4 | wells. | | | |
| | | | | |
| 1 | 37. A method of using the device as claimed in claim 4, the | | | |
| 2 | method comprising: | | | |
| 3 | dispensing a first membrane solution droplet into each of the first | | | |
| 4 | array of wells; and | | | |
| 5 | dispensing a second membrane solution droplet over each of the first | | | |

membrane solution droplets and into each of the second array of wells.